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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

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3-18.00

Assignee:

Nanometrics Incorporated

Title:

MAR 1 3 2000

SYSTEM USING A POLAR COORDINATE STAGE AND

CONTINUOUS IMAGE ROTATION TO COMPENSATE FOR STAGE

ROTATION

Serial No.:

09/113,484

Filed:

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ASSISTANT COMMISSIONER FOR PATENTS Washington, D. C. 20231

INFORMATION DISCLOSURE STATEMENT WITH CERTIFICATION UNDER § 1.97(e)(1)

Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, Applicants wish to call the following documents (copies enclosed) to the attention of the Examiner. The documents were cited in the enclosed European Search Report for the corresponding European Application No. 99305471.7:

- 1. Judell et al. (4,457,664)
- 2. Egan (4,907,880)
- 3. Bacchi et al. (5,646,776)

A PTO form 1449 listing these documents is enclosed.

Citation of the above documents shall not be construed as:

- an admission that the documents are necessarily prior art with respect to the instant invention;
- 2. a representation that a search has been made, other than as described above; or

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3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

The undersigned hereby certifies in accordance with § 1.97(e)(1) that each item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this information disclosure statement.

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: ASSISTANT COMMISSIONER FOR PATENTS, Washington, D.C. 20231, on March 8, 2000.

Attorney for Applicants

Date of Signature

Respectfully submitted,

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